



PATENT  
1028-0171P

2881  
161

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Raymond P. BOISSEAU et al. Conf.: 7224  
Appl. No.: 09/822,864 Group: 2881  
Filed: April 2, 2001 Examiner: KIET T. NGUYEN  
For: METHOD AND SYSTEM FOR CONTROLLING BEAM  
SCANNING IN AN ION IMPLANATION DEVICE

STATUS INQUIRY

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

February 18, 2005

Sir:

Please advise the undersigned as to the status of the above-identified application as follows:

A duplicate copy of the present Status Inquiry is attached hereto. It is respectfully requested that the duplicate copy be marked appropriately to indicate the status of the above-identified application and returned to the undersigned as soon as possible.

Please contact the undersigned if there are any questions with regard to the present request.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

By

Michael R. Mutter, #29,680

MKM/MRG:tm  
1028-0171P

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- ☐ Awaiting Action from Patent Office Examiner - Expected Date for Action is: \_\_\_\_\_.
- ☐ Awaiting Decision by Board of Appeals.
- ☐ Application allowed on \_\_\_\_\_.
- ☐ Abandoned per \_\_\_\_\_.
- ☐ Other \_\_\_\_\_.